PROCEEDINGS OF SPIE

Advanced Laser Processing and Manufacturing

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13 October 2016
Beijing, China

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Volume 10018

Proceedings of SPIE 0277-786X, V. 10018

Advanced Laser Processing and Manufacturing, edited by Minlin Zhong, Jonathan Lawrence,
Minghui Hong, Jian Liu, Proc. of SPIE Vol. 10018, 1001801 · © 2016 SPIE ·
CCC code: 0277-786X/16/$18 · doi: 10.1117/12.2267261

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Please use the following format to cite material from these proceedings:
Author(s), "Title of Paper," in *Advanced Laser Processing and Manufacturing*, edited by Minlin Zhong, Jonathan Lawrence, Minghui Hong, Jian Liu, Proceedings of SPIE Vol. 10018 (SPIE, Bellingham, WA, 2016) Seven-digit Article CID Number.

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510604551
ISBN: 9781510604568 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
SPIE.org

Printed in the United States of America.

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